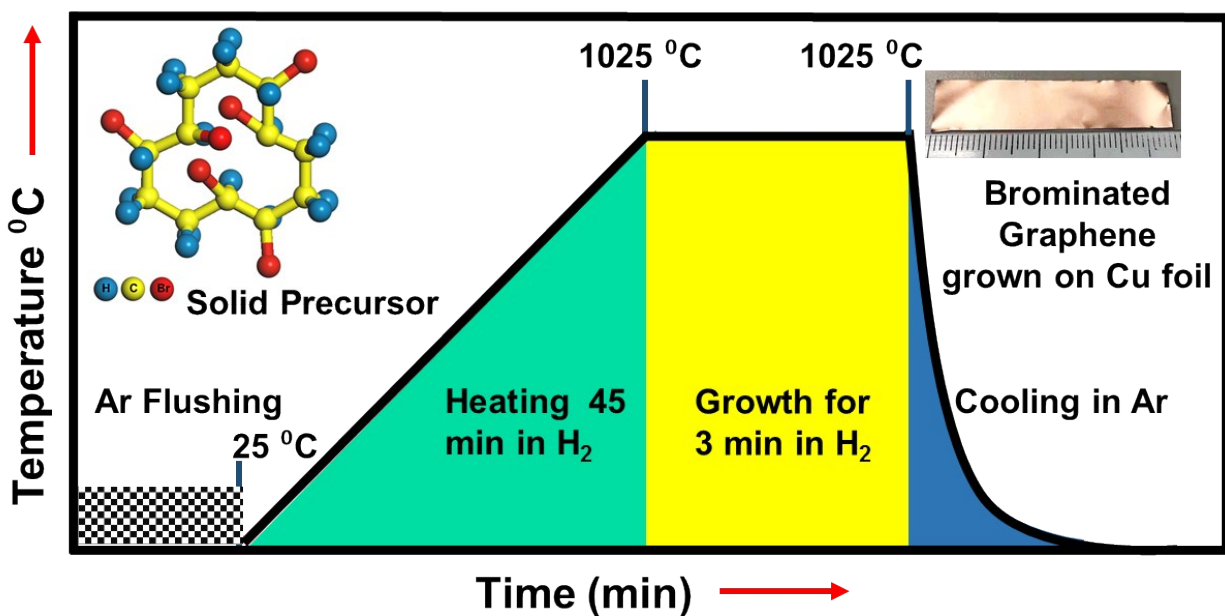


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# Direct Chemical Vapor Deposition Synthesis of Large Area Single-layer Brominated Graphene

Maria Hasan<sup>1,6</sup>, Wang Meiou<sup>2</sup>, Liu Yulian<sup>2</sup>, Sami Ullah<sup>2</sup>, Huy Q. Ta<sup>2</sup>, Liang Zhao<sup>2,3</sup>, Rafael G. Mendes<sup>4</sup>, Zahida P. Malik<sup>6</sup>, Nasir M. Ahmad<sup>7</sup>, Zhongfan Liu<sup>1</sup>, Mark H. Rummeli<sup>2,3,4,5\*</sup>



Electronic Supplementary Information

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Brominated Graphene**

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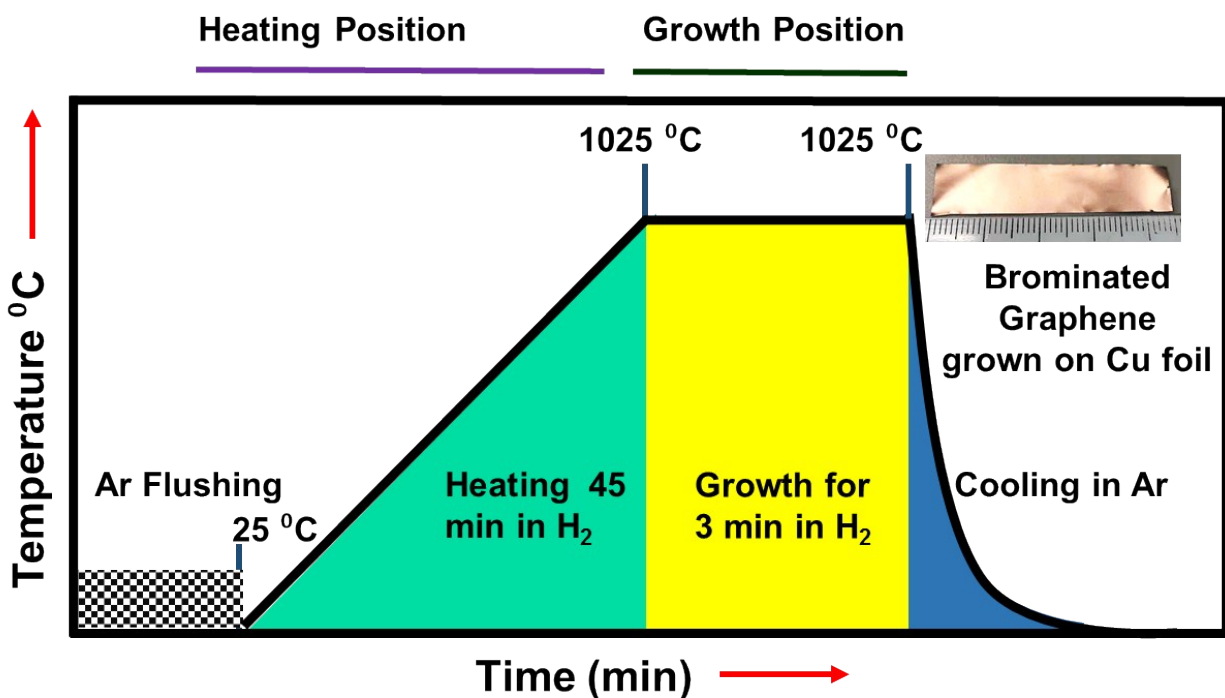


Figure S1. LPCVD Protocol steps during corresponding oven position

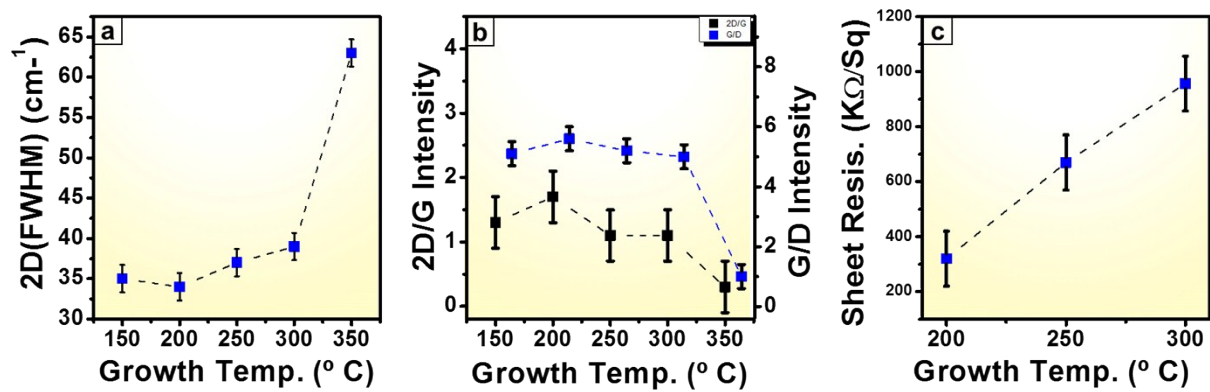


Figure S2. (a) 2D FWHM for the different precursor heating temperature (b) corresponding G/D and 2D/G ratios (c) Corresponding Sheet Resistance (KΩ sq<sup>-1</sup>)

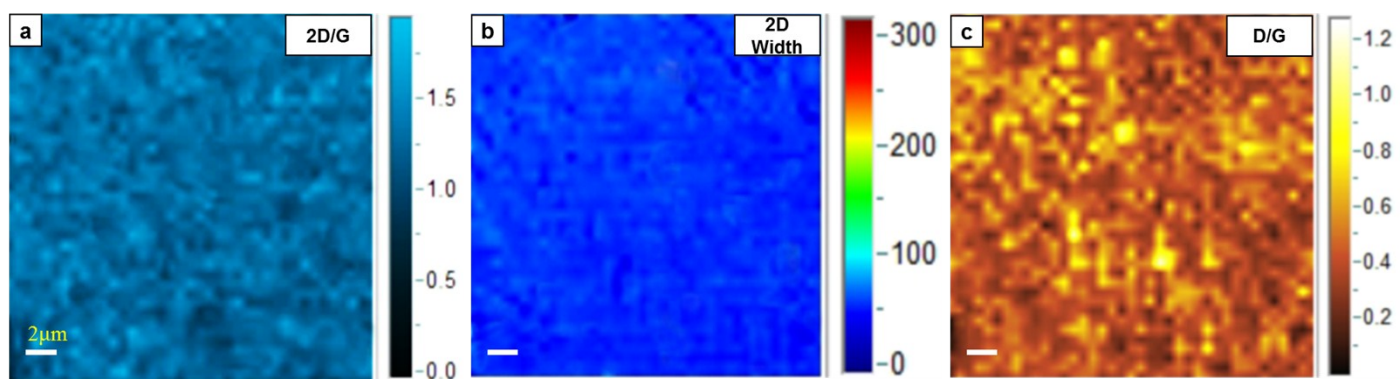


Figure S3. Raman area mapping of (a) 2D/G ratio (b) 2D width (c) D/G ratio. Scale bar 2 μm.

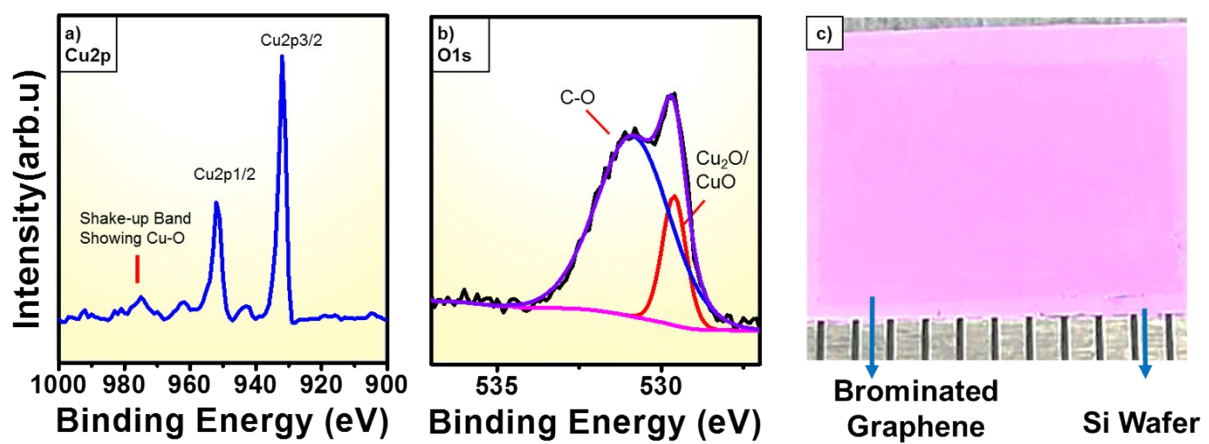


Figure S4. (a) High resolution Cu2p spectrum (b) High Resolution O1s spectrum (c) Large area brominated graphene (1×1 cm) after transfer to a silicon wafer